



SEC.760

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re PATENT APPLICATION of:

Seung-pil Chung et al.

Group Art Unit: 1763

Serial No.: 09/689,814

Examiner: L. Alejandro Mulero

Filed: 13 October 2000

METHOD FOR REMOVING OXIDE  
LAYER AND SEMICONDUCTOR  
MANUFACTURING APPARATUS  
FOR REMOVING OXIDE LAYER

H12B  
4/15/03  
mw

**AMENDMENT UNDER 37 C.F.R. § 1.116**

Honorable Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated 20 December 2002, and concurrent with  
the Request for Continued Examination under 37 C.F.R. § 1.114 filed herewith,  
please amend the above-identified patent application as follows:

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TC 1700

**IN THE CLAIMS:**

Please substitute the following claims for the pending claims with the same  
claim numbers.

7. (Amended) A semiconductor manufacturing apparatus for use in removing  
an oxide layer, comprising:  
a vertically movable susceptor installed at a lower portion of a processing